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10/582343 Sheet 1 of 1

Form PTO-1449 (REV. 1/06)		US Dept. of Commerce PATENT & TRADEMARK OFFICE ATION DISCLOSURE STATEMENT		ATTY I 128275	DOCKET NO.	10	APPLICAT New US 1 Stage of PCT/FR20	atiogal 43	
(Use several sheets if necessary)				APPLICANT Philippe ROBERT					
				FILING June 9,	DATE				
U.S. PATENT DOCUMENTS									
Examiner Initials	Cite No.	Document Number	Date			Name			
	1	5,090,254	2/25/1992		GUCKEL et al.				
			 						
									
FOREIGN PATENT DOCUMENTS									
Examiner Initials	Cite No.	Document Number	Da		Country		With English Abstract	With English Translation	
	2	DE 100 05 555 A	8/16/200	1	GERMANY				
	3	EP 0 451 992 A	10/16/19	91	EUROPE				
OTHER DOCUMENTS									
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	4 M. BARTEK et al., "Vacuum sealing of microcavities using metal evaporation," Sensors and Actuators A, vol. 60, n								
		pp. 364-368 (May 1, 1997).							
	5 M. FURTSCH et al., "Texture and stress profile in thick polysilicon films suitable for fabrication of microstructure								
		Thin Solid Films, vol. 296, no. 1-2, pp. 177-180 (March 1, 1997).							
" ' ' ' ' '									
EXAMINER	EXAMINER /Kevin Parendo/					DATE CONSIDERED 03/06/2000			
Examiner:	Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								

Date: June 9, 2006 ALL REFERENCES CONSIDERED EXCEPT WHERE LINED THROUGH. /K.P./